

HIGH FLUX VALUE MICRO HEAT PIPE ARRAYS

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Why Liquid Metal Micro Heat Pipes (MHPs)

- Phase Change Heat Transfer
- High Heat Flux Ability Using Liquid Metals
- Embedded Directly Under Electronics Heat Source
- Good Si or Ceramic CTE Matching Abilities

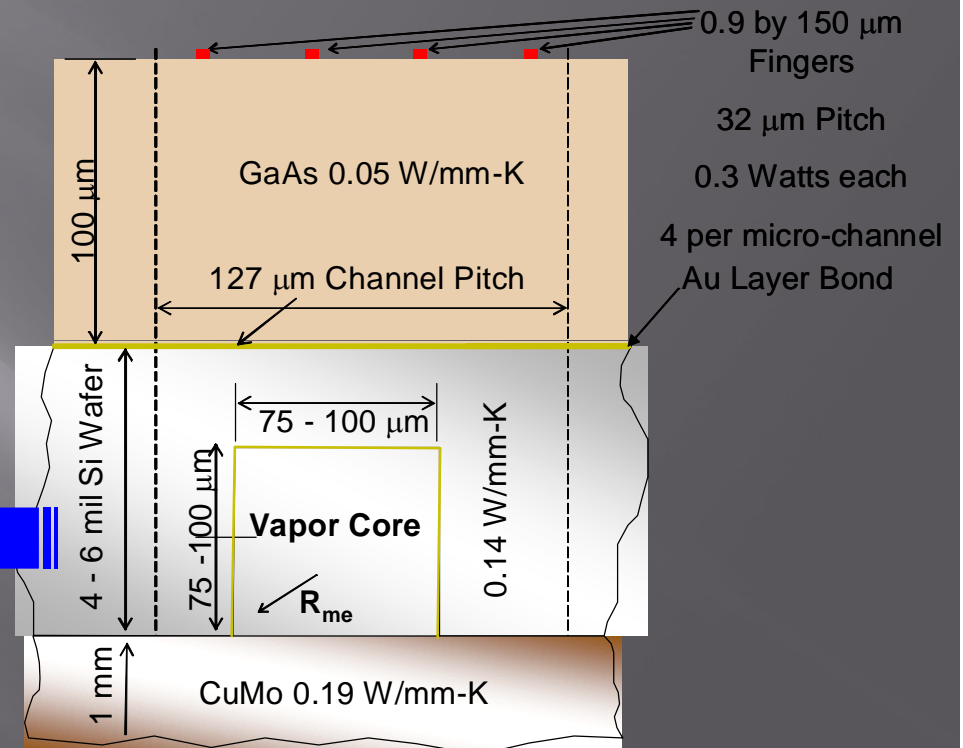
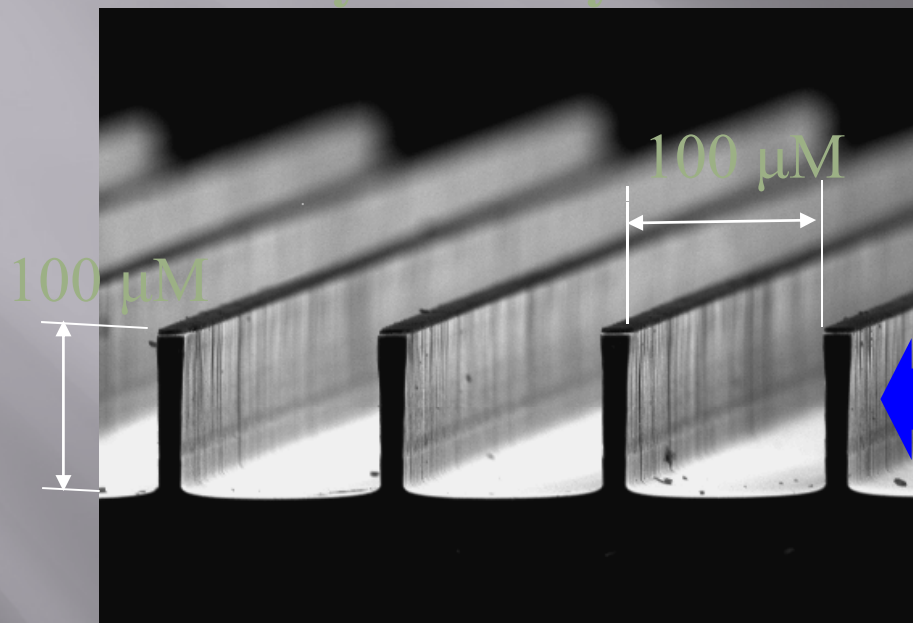
Introduction

III. Micro Heat Pipes (MHPs):

- ▣ Concept was first introduced by **Cotter** in 1984
- ▣ Cotter defined micro heat pipe as being “ the one in which the mean curvature of the vapor-liquid interface is comparable in magnitude to the reciprocal of the hydraulic radius of the total flow channel”
- ▣ The basic working mechanism is same as the heat pipes, the **distinguishing** factor being the **omission** of the “**wick**” structure
- ▣ Characteristic small sizes, makes MHPs **suitable** for the **semi-conductor** industry applications

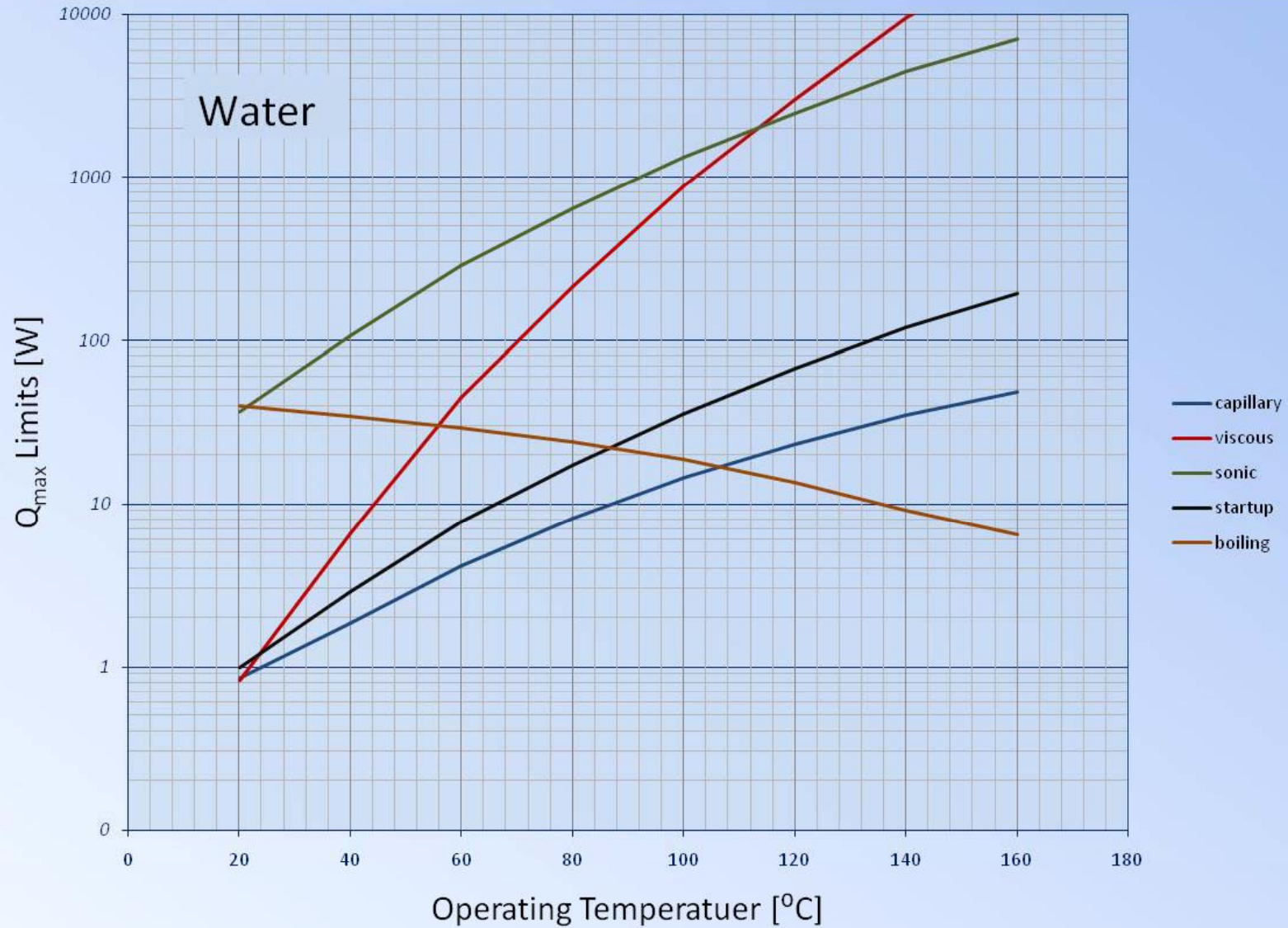
Micro-heat Pipes in Si Heat Spreaders

22 micro-channels in an array 5 mm by 10 mm



- DREI etch process performed in Auburn University micro-machining laboratory
- Process is well characterized and very repeatable in a manufacturing environment

Operational Limits for Water μ HPs

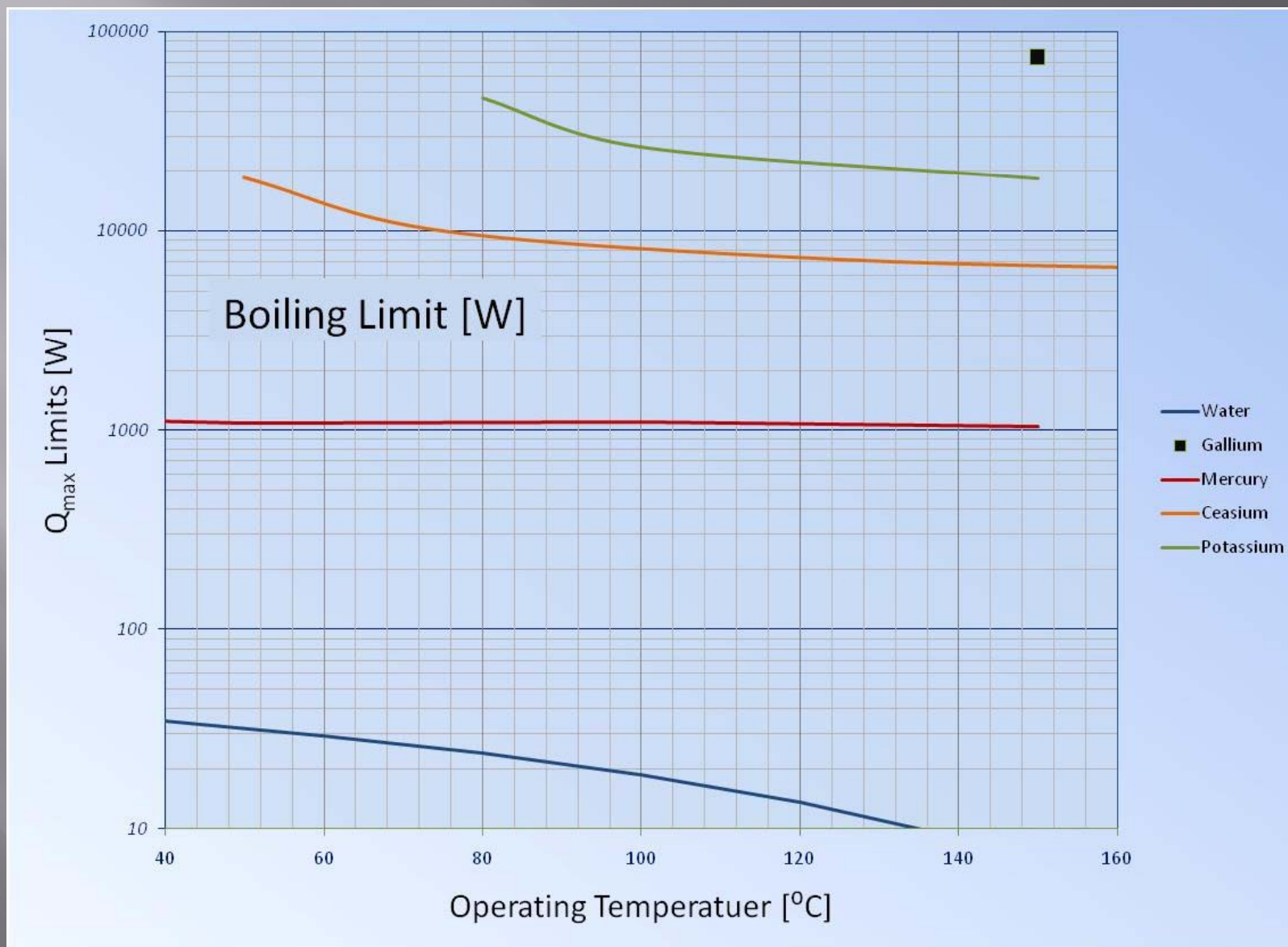


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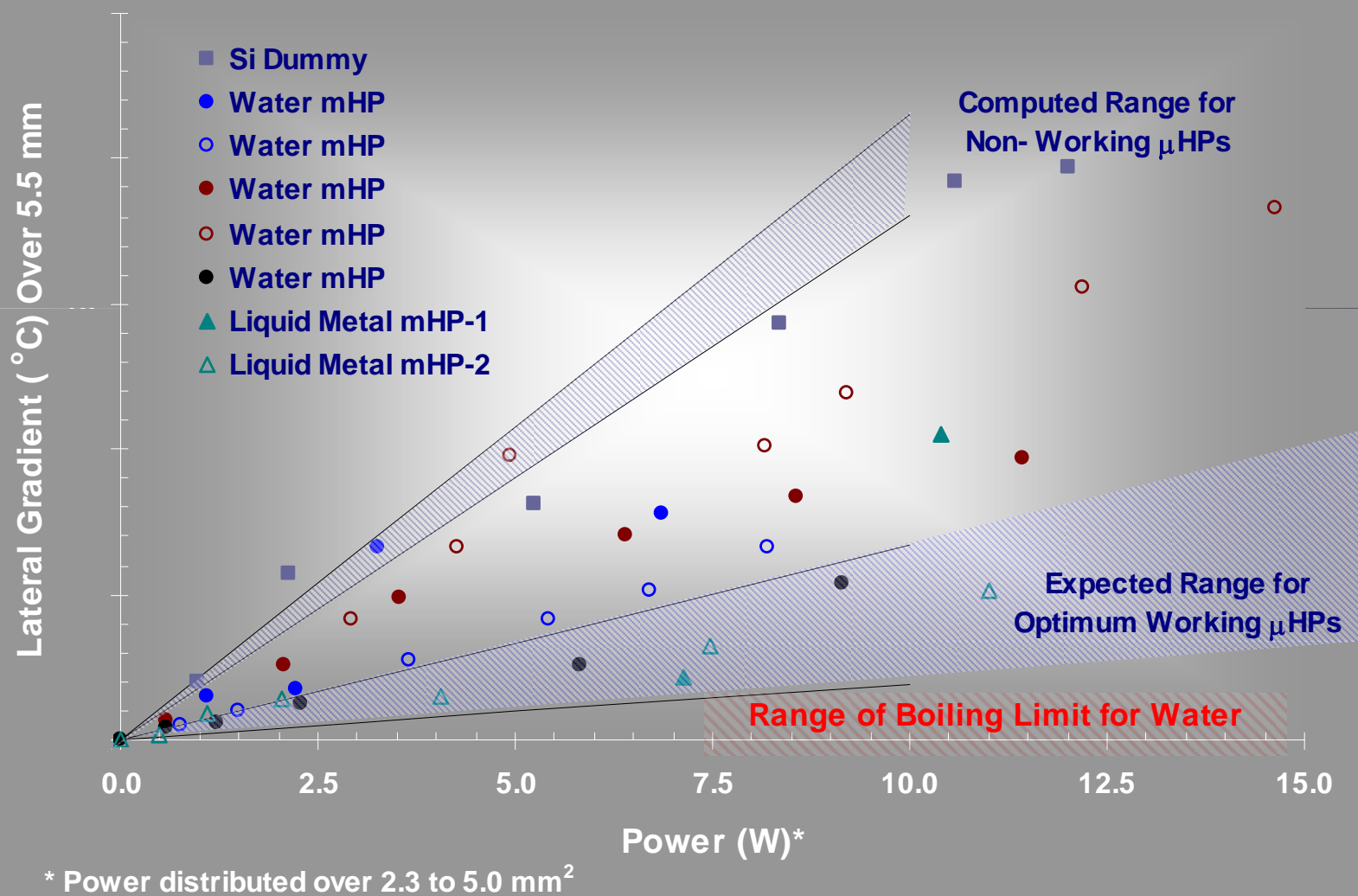
Boiling Limit Comparison



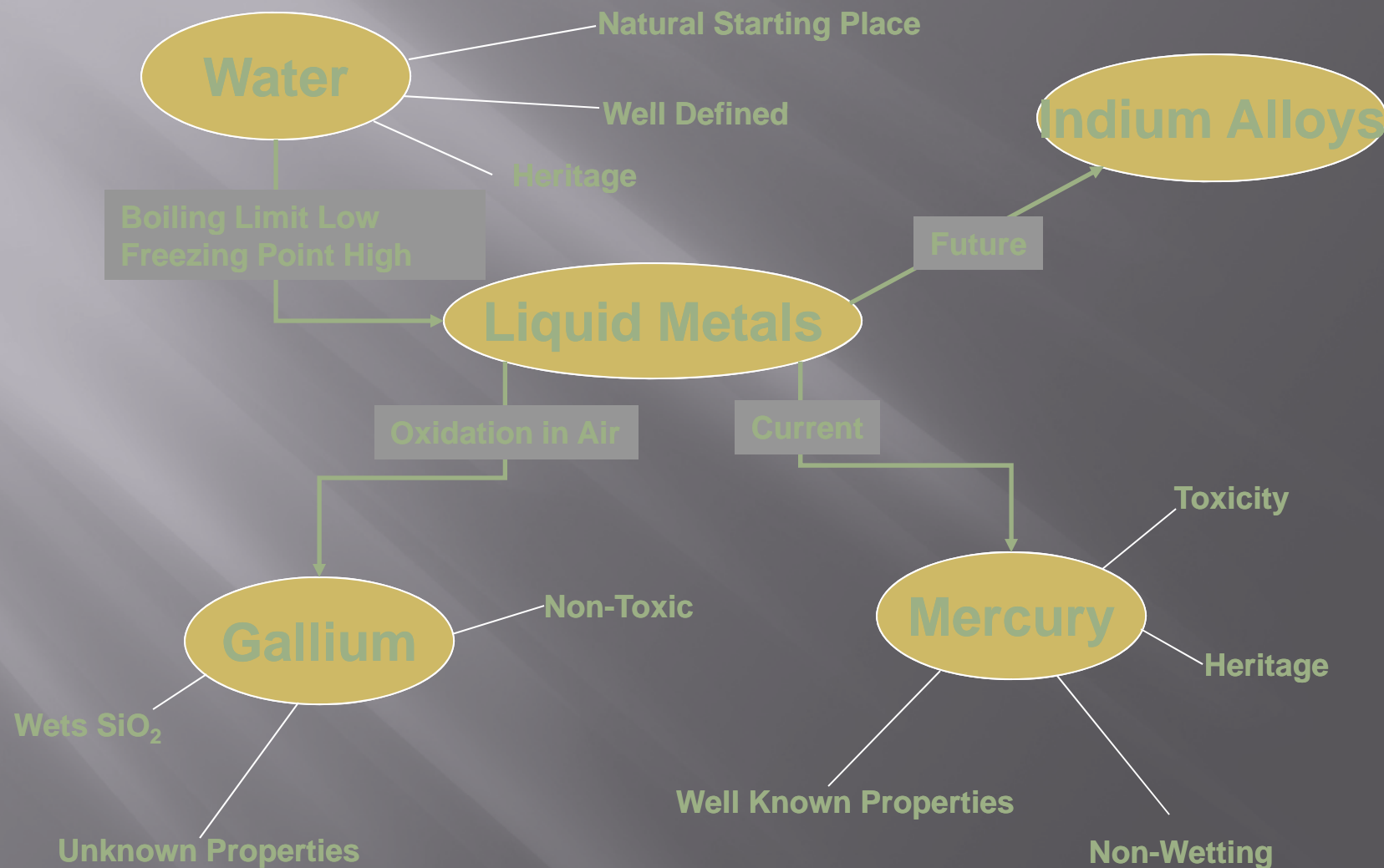
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The Liquid Metal Advantage



Working Fluid Decision Tree



Driving Parameter – Critical Heat Flux

Incipient Site Radius	2.54×10^{-7}	50 Å
3M FCs	0.34 W/mm ²	
Water	1.2 W/mm ²	2.4 W/mm ²
Thermex ^{100°C}		3.2 W/mm ²
Mercury ^{100°C}	26 W/mm ²	46 W/mm ²
In-Ga Eutectic ^{100°C}		34 W/mm ²

Liquid Metal Working Fluids

- ▣ Liquid Metal MHPs Give Superior Performance.
 - ▣ B. Badran, et al., "Liquid-Metal Micro Heat Pipes," **Proceedings of the 29th National Heat Transfer Conference**, August 8-11, 1993, HTD Vol. 236, pp. 71-85 [4]
- Looked at Mercury, Sodium, Potassium
 - ▣ Hg (-38.4 C) Good Candidate
 - ▣ Na (97.8 C) T_{melt} Too High
 - ▣ K (63.7 C) T_{melt} Too High

Benefits

- ▣ Higher Boiling Limit
- ▣ Higher Heat Transfer Performance – ref. [4]

	Melting Point	Specific Thermal Conductance*
Mercury	-38.4 °C	124
Sodium	97.8 °C	630
Potassium	63.7 °C	504

- ▣ Material Compatibility
- ▣ Commercially Available

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Other Options Include Indium Based Eutectics...

- ▣ Low Liquidus Temperature
- ▣ High Surface Tension
- ▣ Wets Si, SiO₂
- ▣ High Liquid Thermal Conductivity

Indalloy Number	Liquidus °C	Solidus °C	Elemental Composition (% by Mass)
60	15.7	15.7	75.5 Ga/24.5 In
77	25	15.7	95 Ga/5 In
14	29.8		100 Ga
18	61.5	61.5	61.72 In/30.78 Bi/7.5 Cd
162	72	72	66.3 In/33.7 Bi
25	77.5	77.5	48.5 Bi/41.5 In/10 Cd

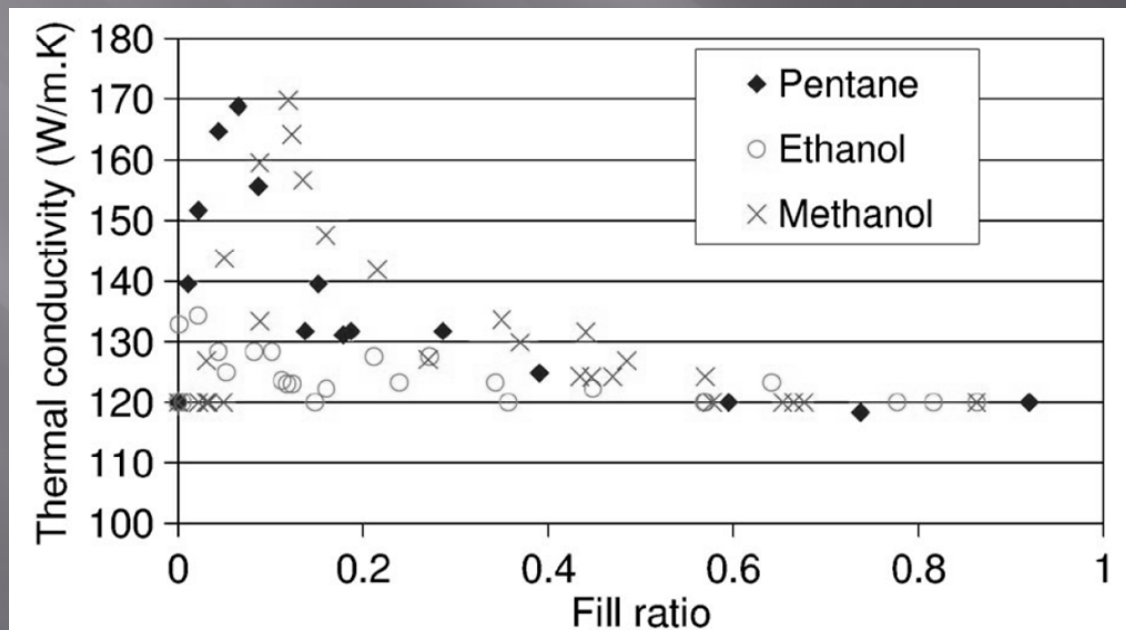
...And Gallium

- ▣ Ga
 - Unknown transport properties
 - Performance is not predictable
 - No heritage from heat pipe literature
 - Higher freezing point ($\sim 30^\circ\text{C}$)
 - Low vapor density and pressure
 - No known safety concerns
 - Easier for sealing due to solid state during evacuation.

Factors Affecting the Working of MHPs

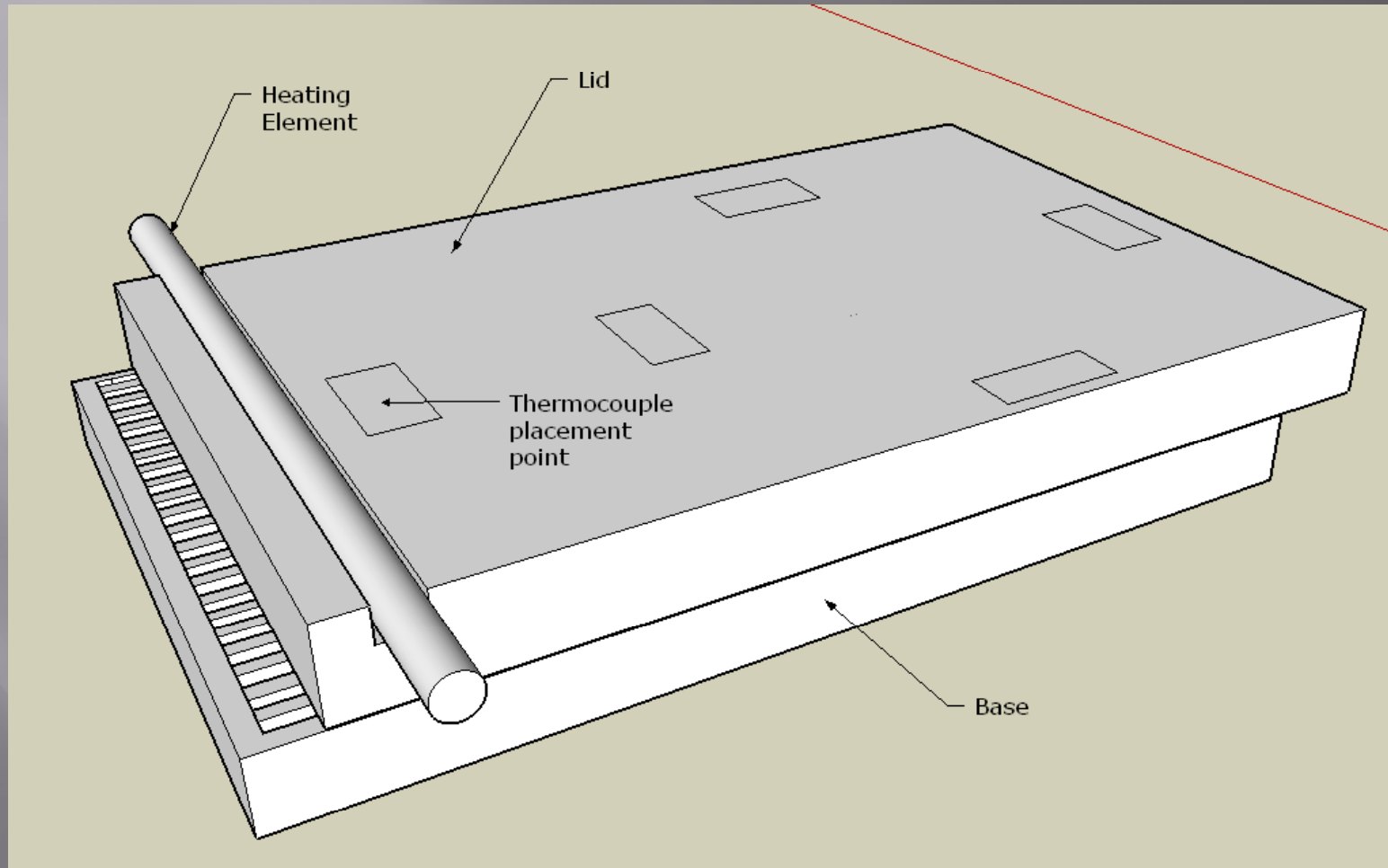
IV. Charge of the MHP:

- It is the **amount** of working fluid **filled** into the MHP
- Best performances** of MHPs were recorded **with lower** fill ratios rather than with high fill ratios [5]



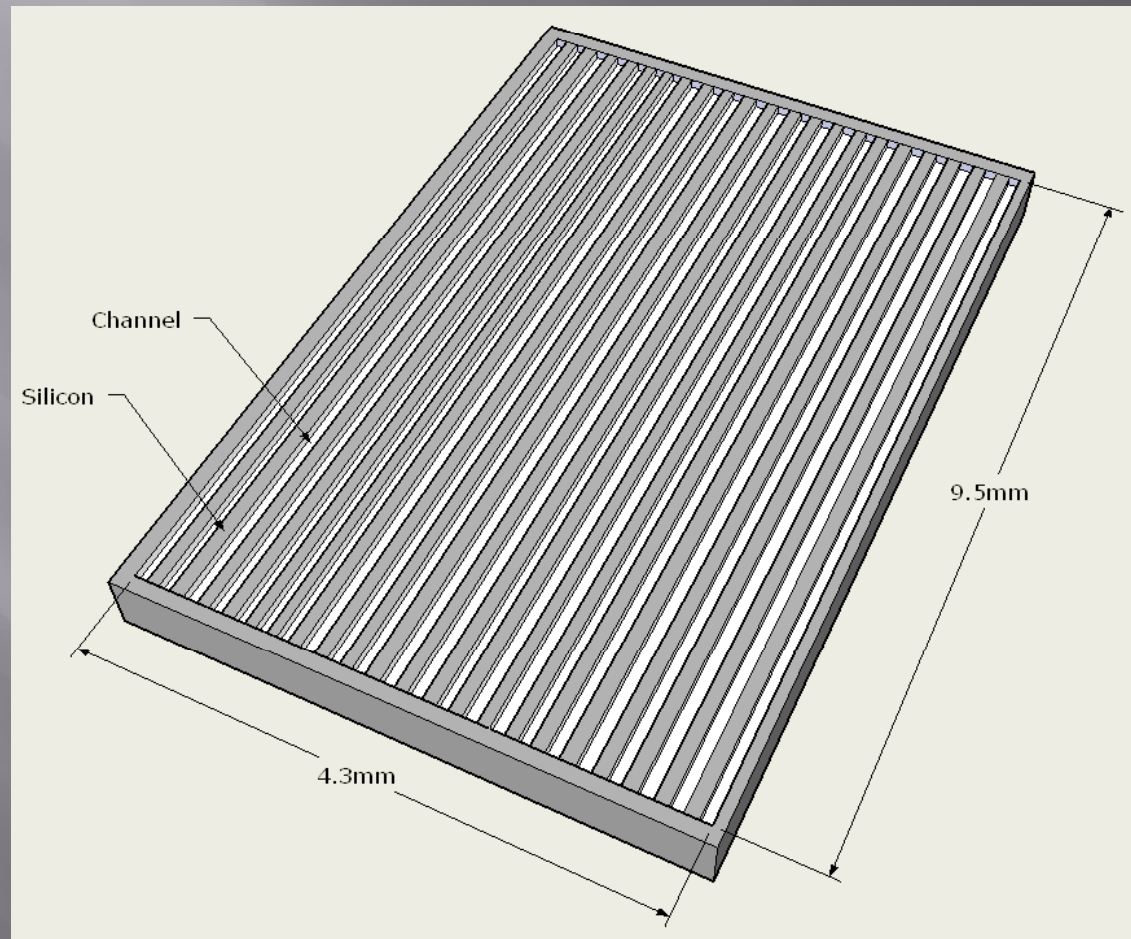
Testing of MHPs

II. Structure and components of the MHP array die:

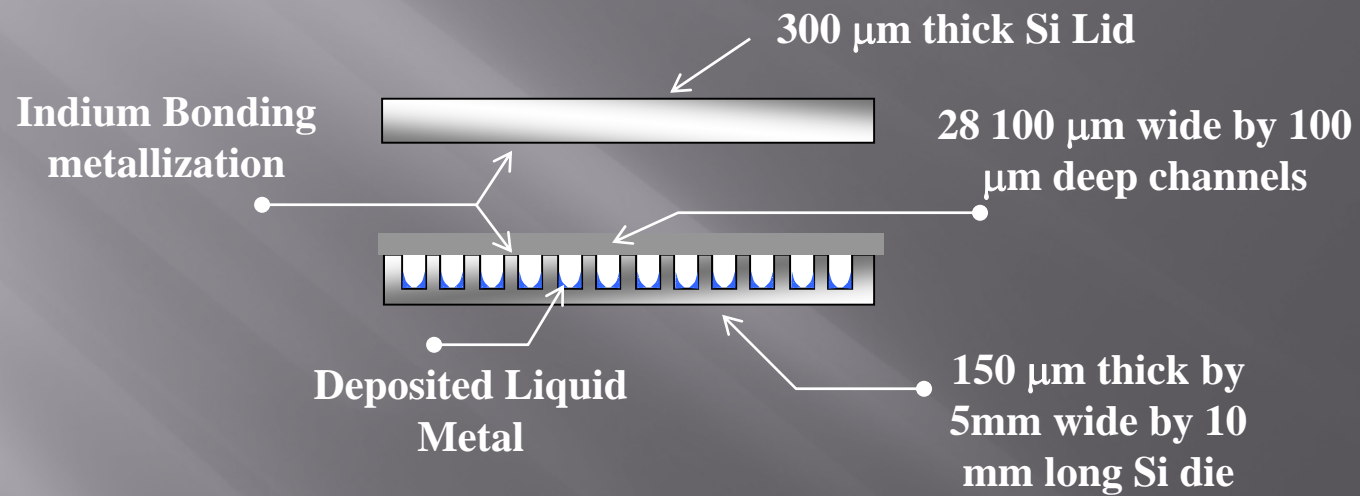


Testing of MHPs

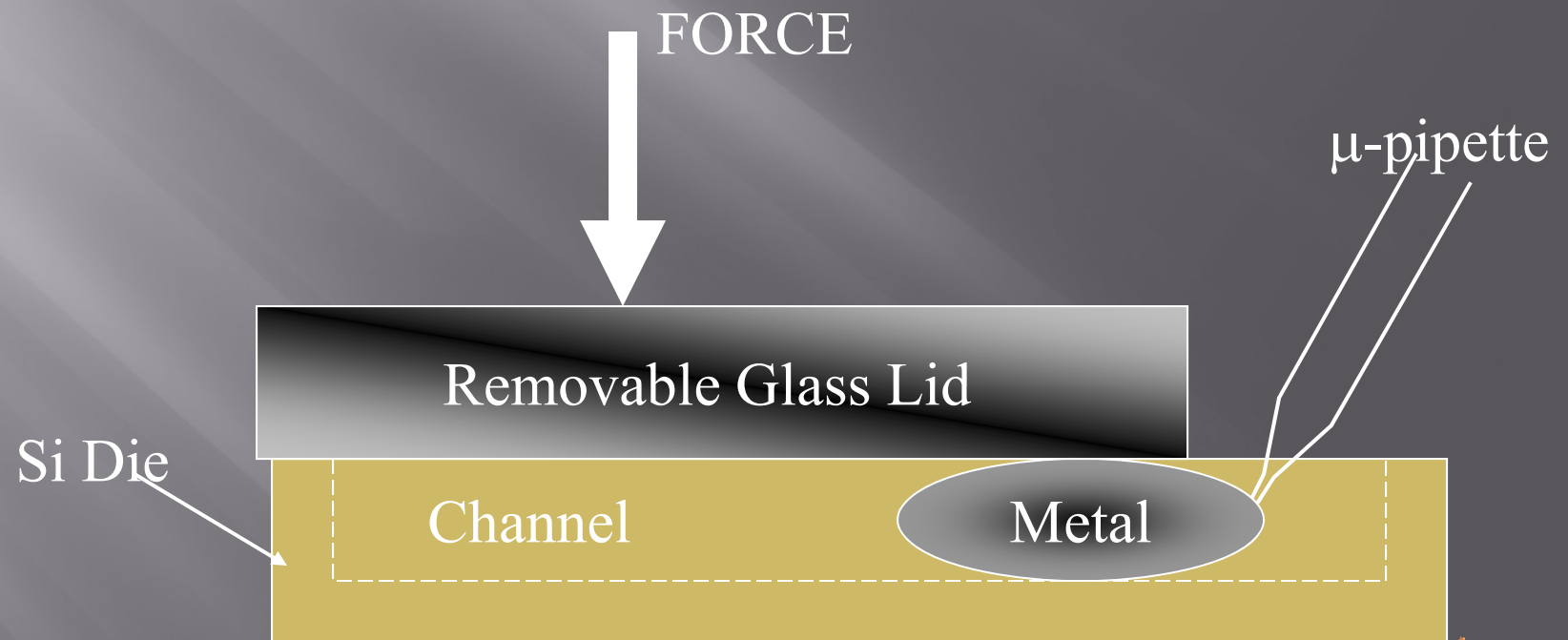
- Base dimensions of the MHP array die



Assembly Cross-Section Dimensions

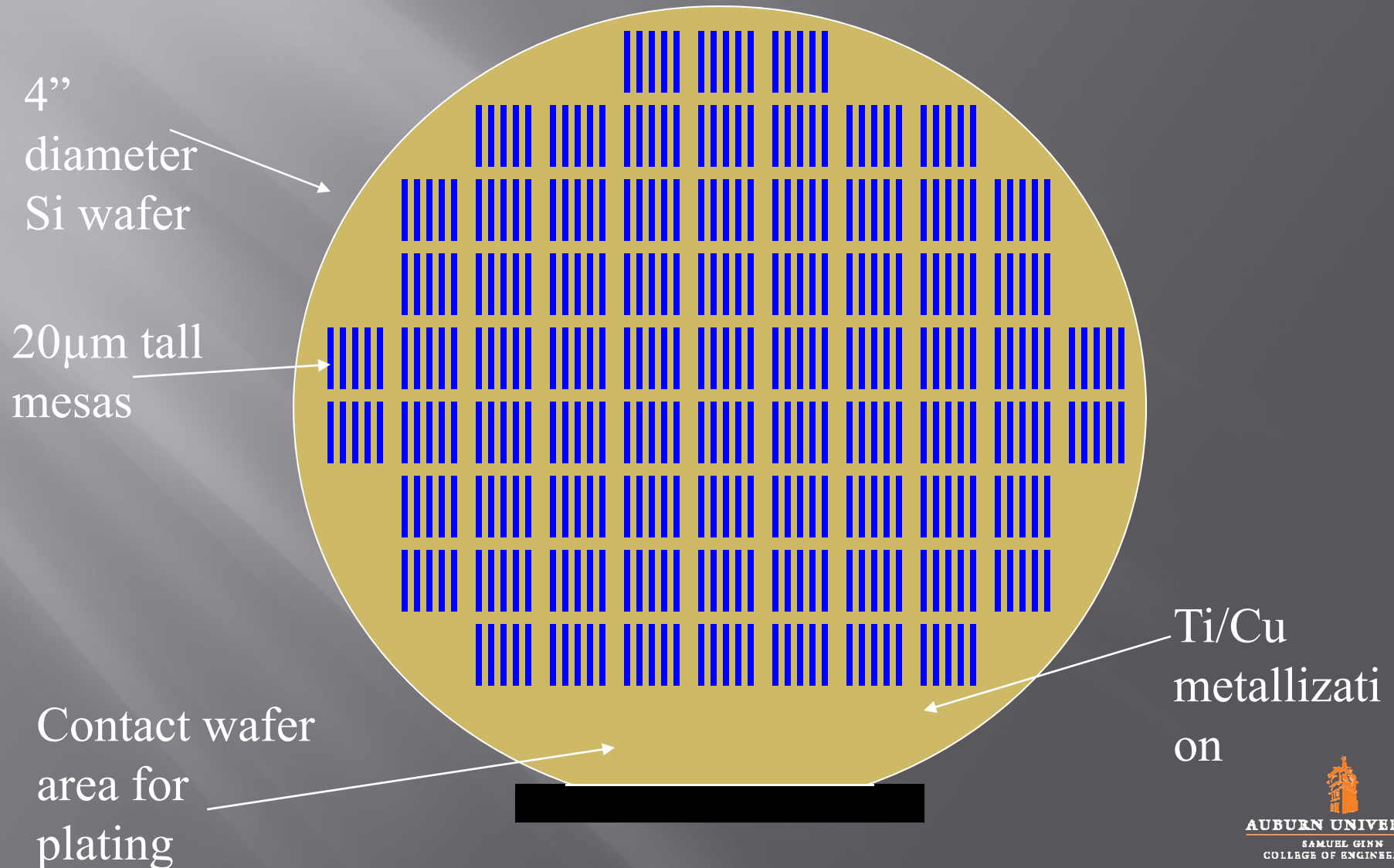


Liquid Metal Filling Technique

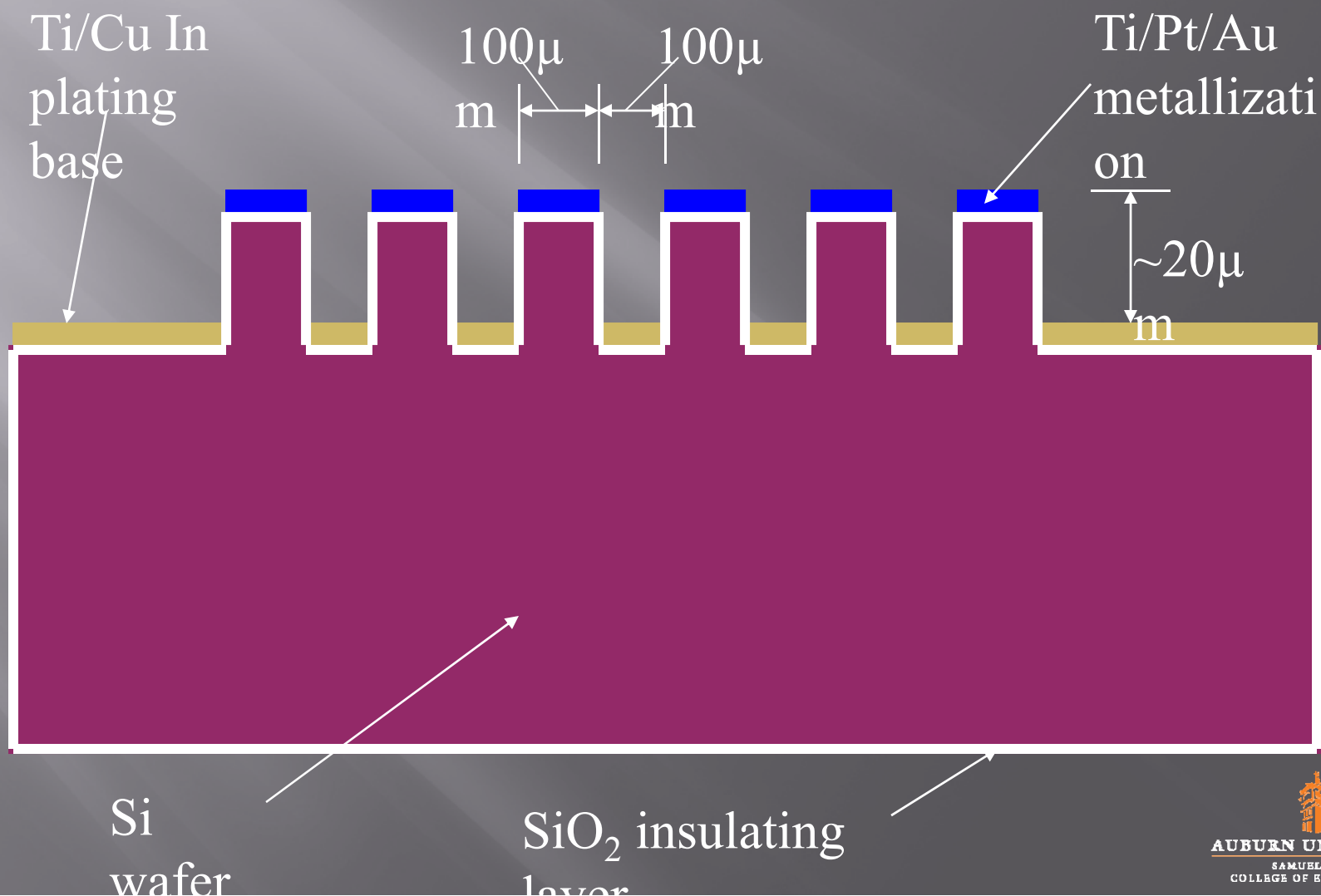


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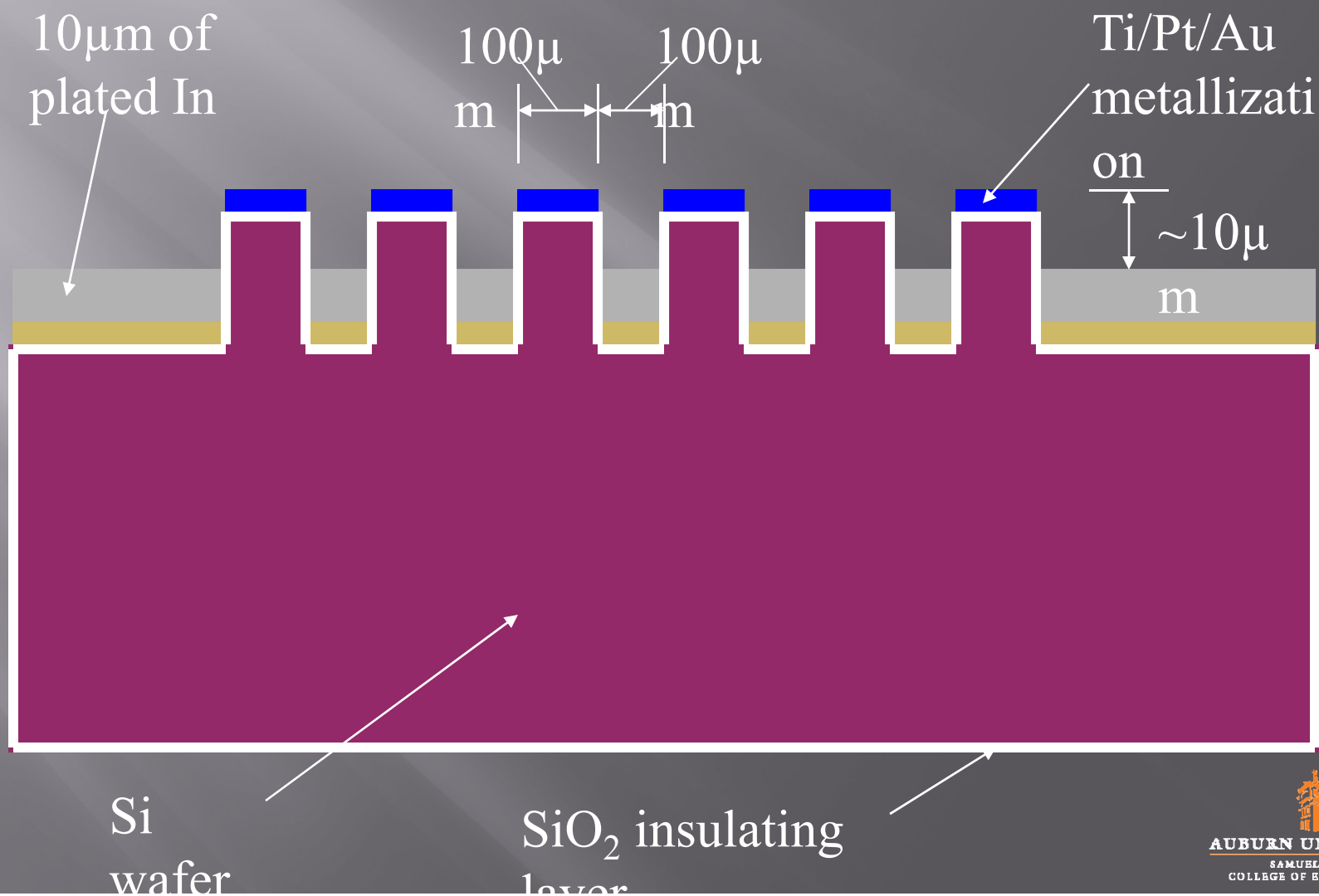
Drawing of Wafer Before Plating



Cross-sectional View Before In Plating



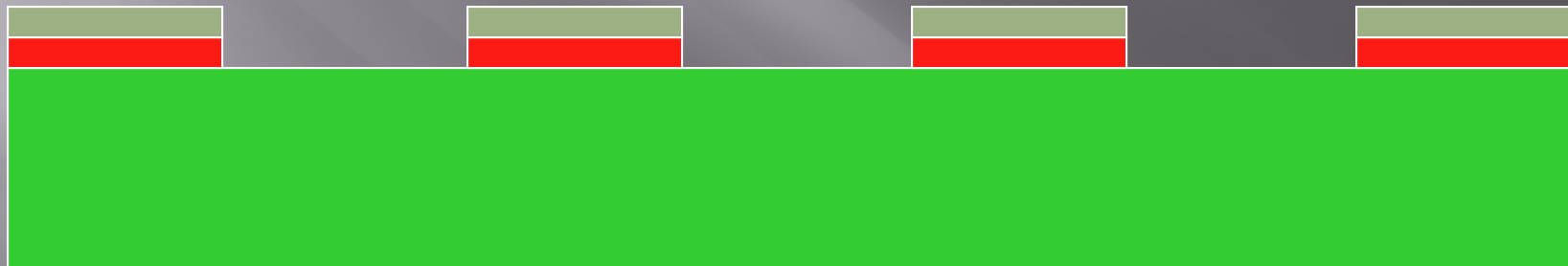
Cross-sectional View After 10 μ m In Plating



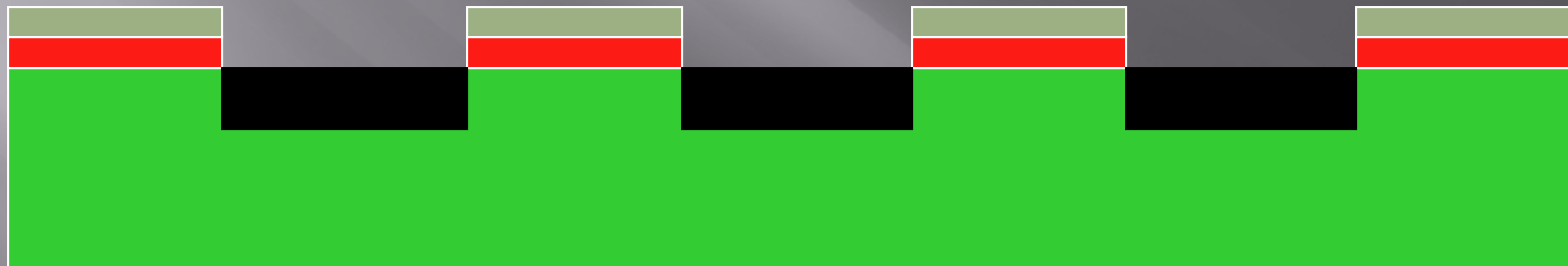
Step 1: Ti/Pt/Pd deposition



Step 2: coat Ti/Pt/Pd with PR and pattern Ti/Pt/Pd (wet etch)



Step 3: 20 μ m DRIE



Step 5: Wash off PR / liftoff



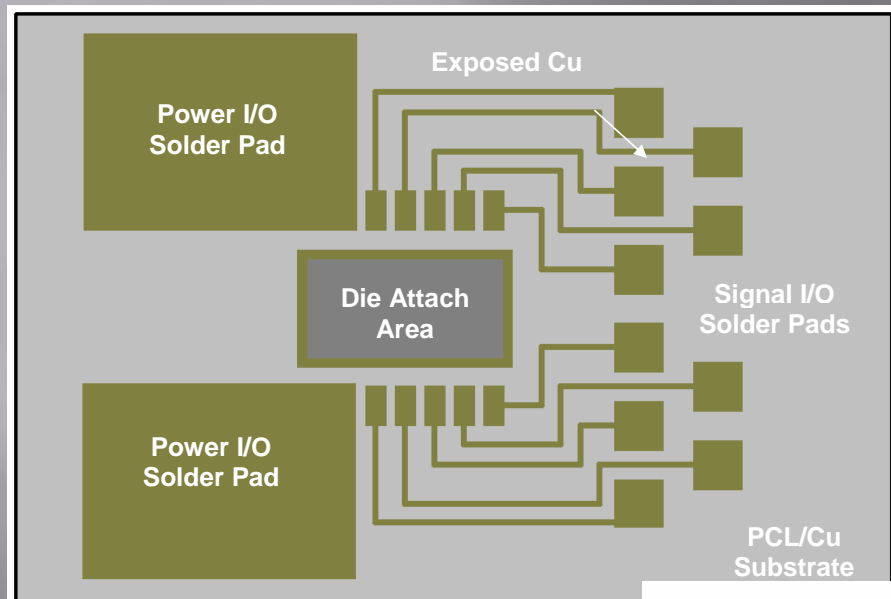
Step 6: Send out for plating



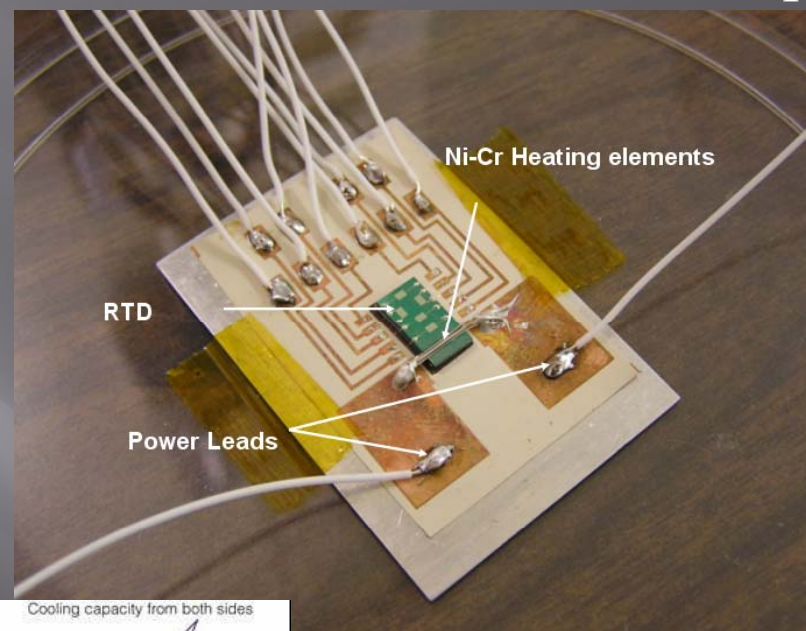
Die Assembly Procedure

- ▣ Etch wafer, saw and clean die
- ▣ Dip into melted metal bath
- ▣ Remove photomask
 - ▣ This step done before dipping for Hg channels
- ▣ Pattern lid
 - ▣ top – thermal sensors
 - ▣ bottom – channel metallization
- ▣ Evacuate and bond lid onto die

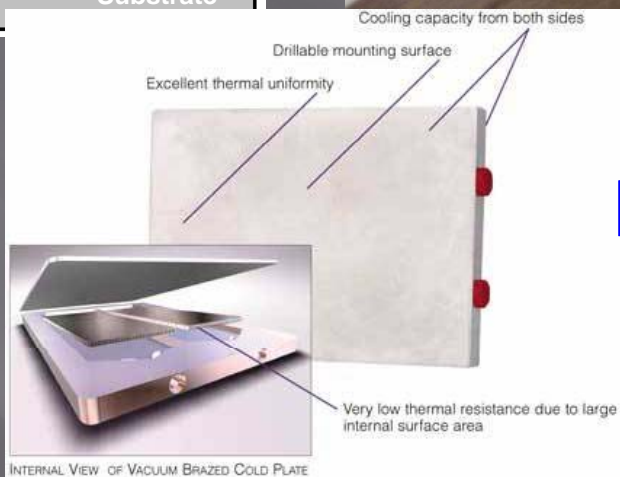
Test Board Design



Fabricated Test Set Up



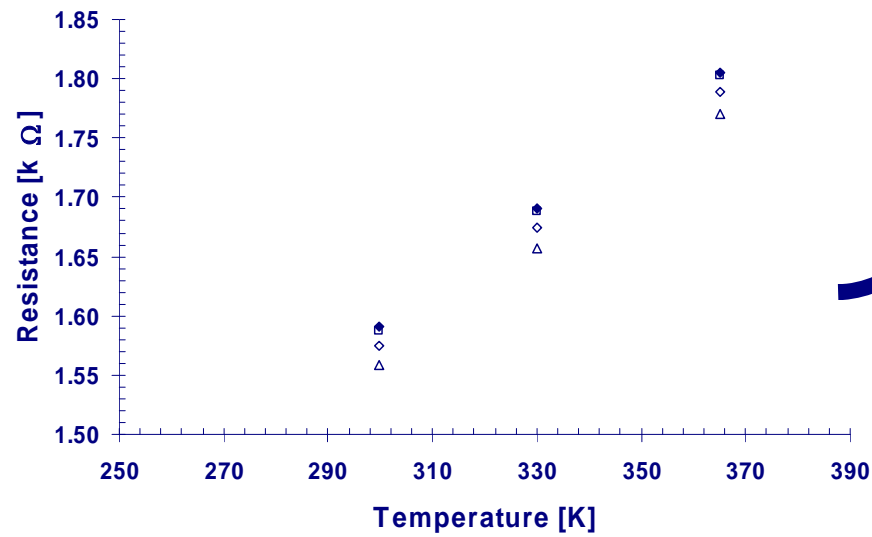
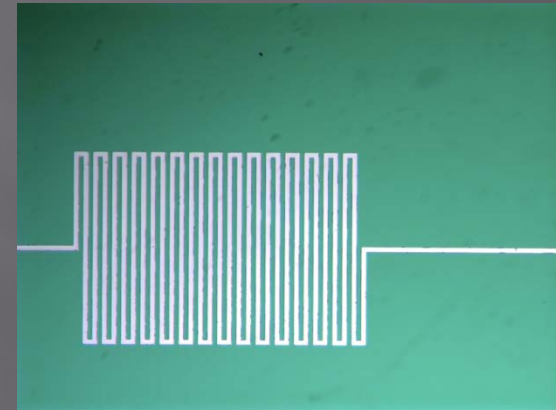
Lytron® Cold Plate



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Platinum RTD Micro-Sensors

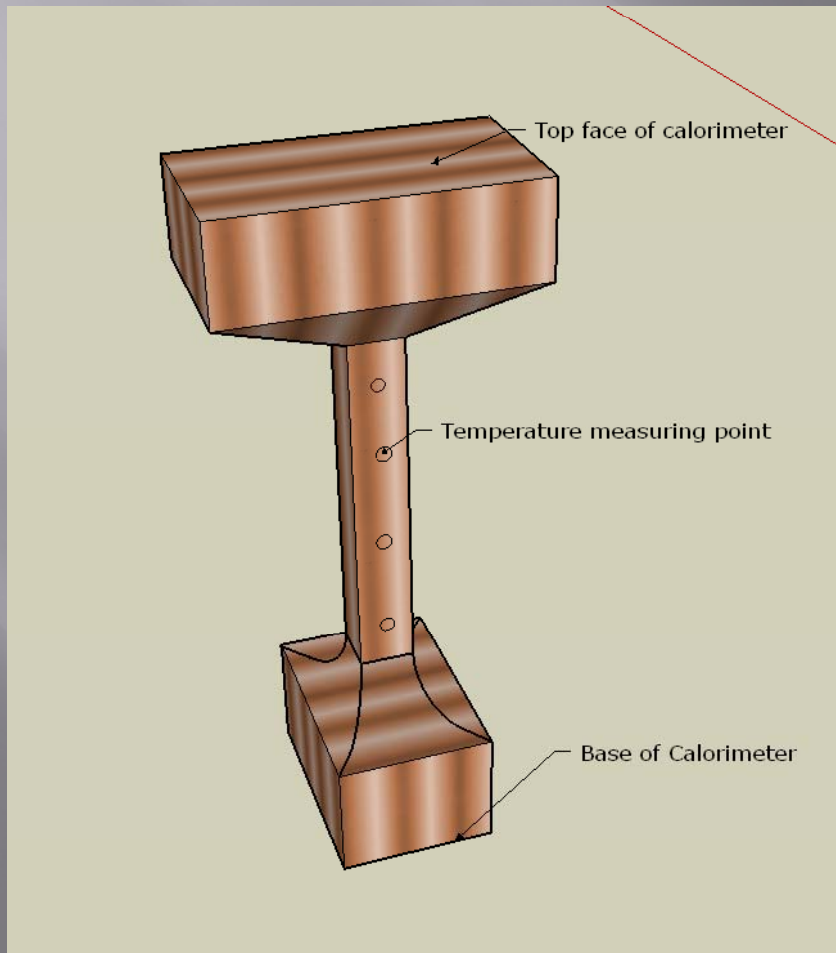
- Non-Production Feature
- 5 per MHP Die.
- Used in Tandem with IR Scope.
- Each Sensor Calibrated



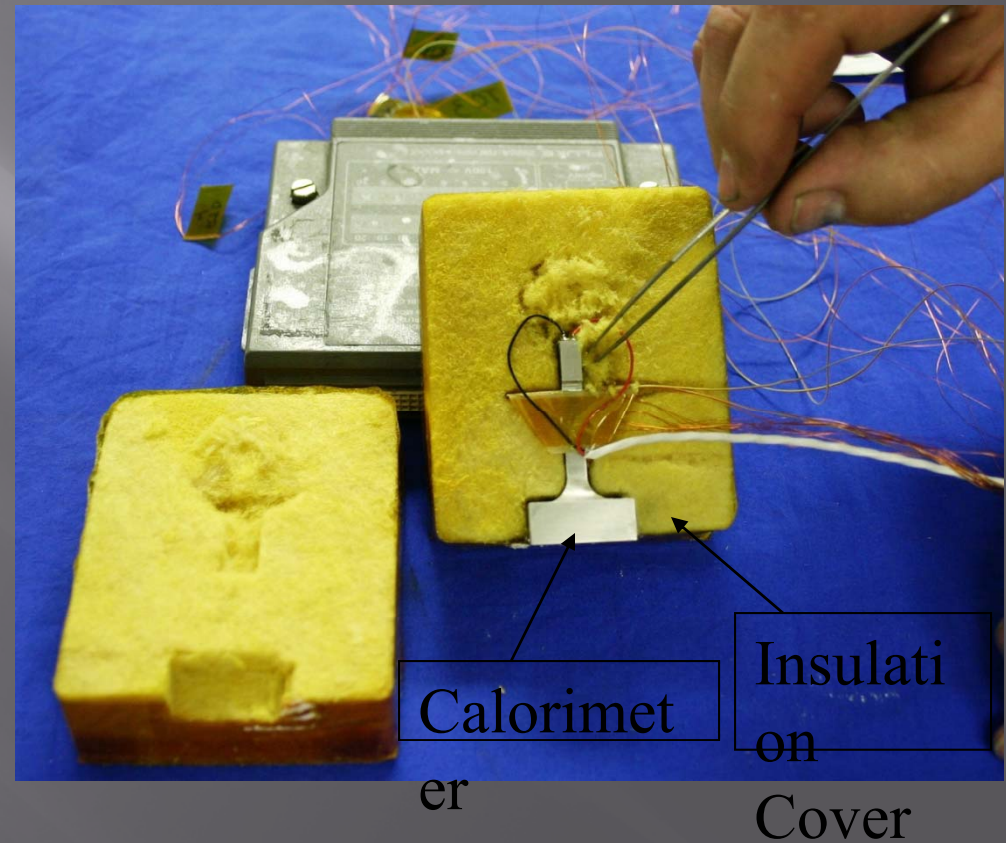
Testing of MHPs

Calorimeter

(a) Model



(b) Within the insulation cover



Test Results

Thermal resistance

$$\text{Thermal Resistance} = \Delta T / \text{Power}$$

Where,

ΔT = Temperature difference between the evaporator and condenser regions of the MHP

Power = Input power to the MHP

Test Results

A. First Method – Silicon Equivalence Method

Calculation of Equivalent Thermal Conductivity Using the Silicon Equivalence Approach

K silicon (W/m-K)	Name	Equation	Slope ($\Delta T/\Delta Q$)	R ² Value	Silicon Equivalence	Equi. Thermal cond. (W/m-K)
148	Empty MHP	1.3968x+0.1111	1.3968	0.9882	1	148.0
	Water filled MHP-1	0.793x-0.2012	0.793	0.9987	1.76	260.7
	Water filled MHP-2	0.638x-0.0643	0.638	0.9987	2.19	324.0
	Silicon/Mercury-1	0.4689x+0.0895	0.4689	0.9836	2.98	440.9
	Silicon/Mercury-2	0.638x-0.0643	0.638	0.9987	2.19	324.0
	Silicon/Mercury-3	0.6525x-0.105	0.6525	0.993	2.14	316.8
	Silicon/Mercury-4	0.2329x+0.0678	0.2329	0.9956	6.00	887.6
	Silicon/Mercury-5	0.246x+0.1009	0.246	0.9954	5.68	840.4
	Silicon/Mercury-6	0.2618x+0.0882	0.2618	0.9898	5.34	789.6
	Silicon/Mercury-7	0.2824x+0.1128	0.2824	0.9963	4.95	732.0
	Silicon/Mercury-8	0.2797x+0.0614	0.2797	0.9978	4.99	739.1
	Silicon/Mercury-9	0.2742x+0.0413	0.2742	0.9978	5.09	753.9
	Silicon/Mercury-10	0.259x+0.2169	0.259	0.9861	5.39	798.2



Test Results

Second Method – Effective thermal conductivity

$$K_{eff} = [(Q / A_{mhp})] / [(T_{max} - T_{min}) / L]$$

Where,

Q = Input power

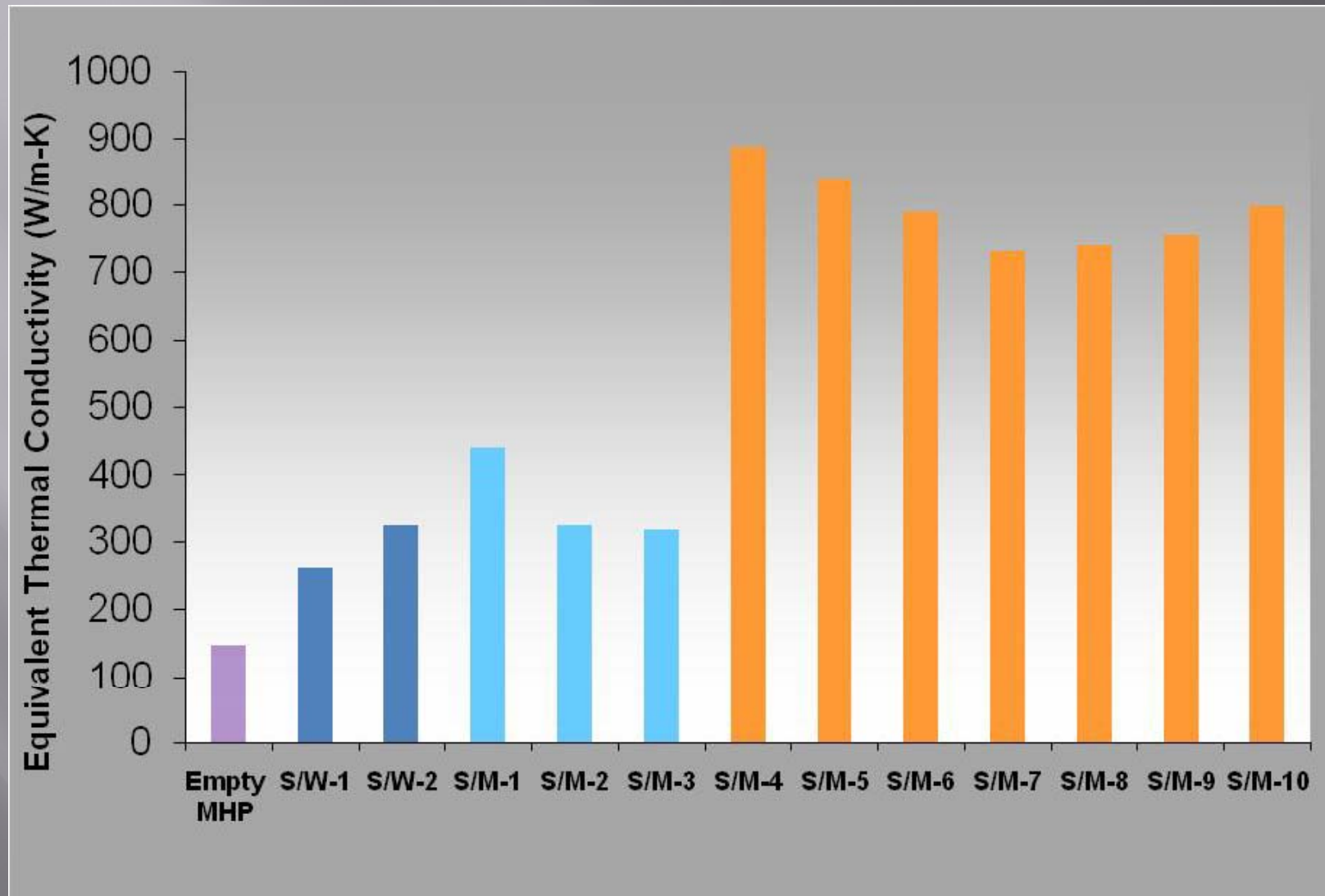
L = Length of the MHP

A_{MHP} = Area of the MHP array

T_{max} = Temperature at evaporator end for given Q

T_{min} = Temperature at condenser end for given Q

Equivalent Thermal Conductivity

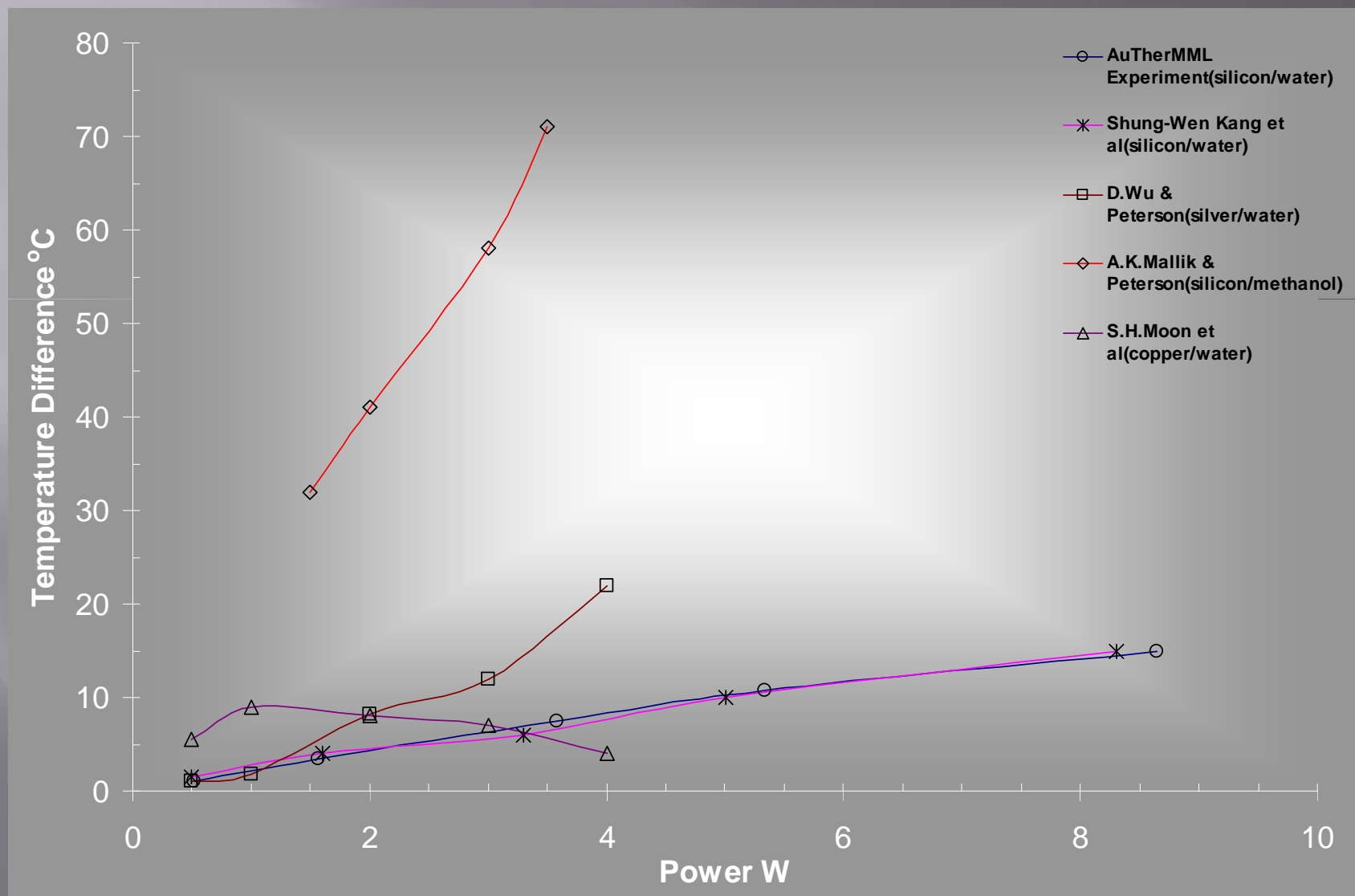


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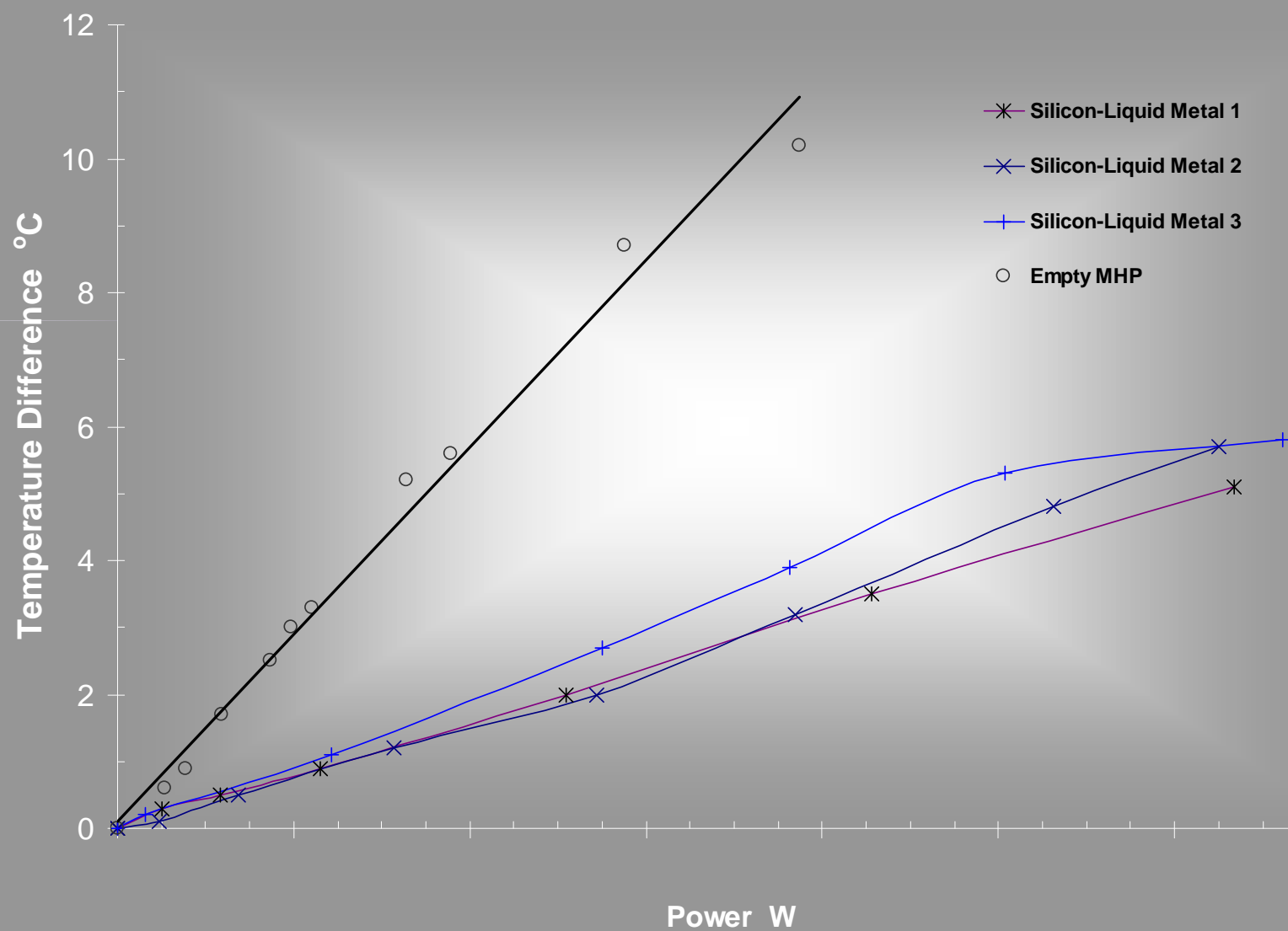
Comparison of Water μ HP Performance



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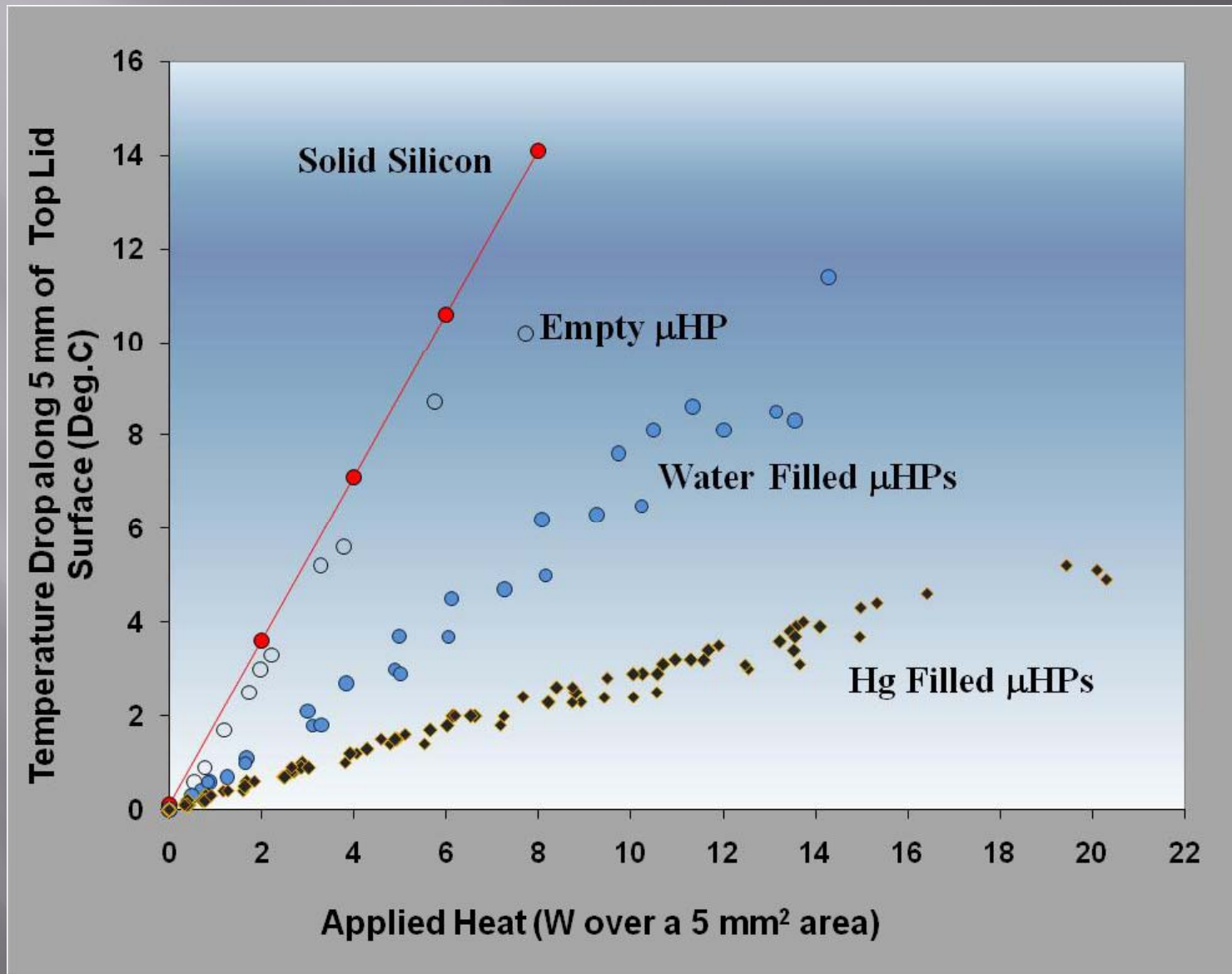
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Liquid Metal Filled μ HP Performance



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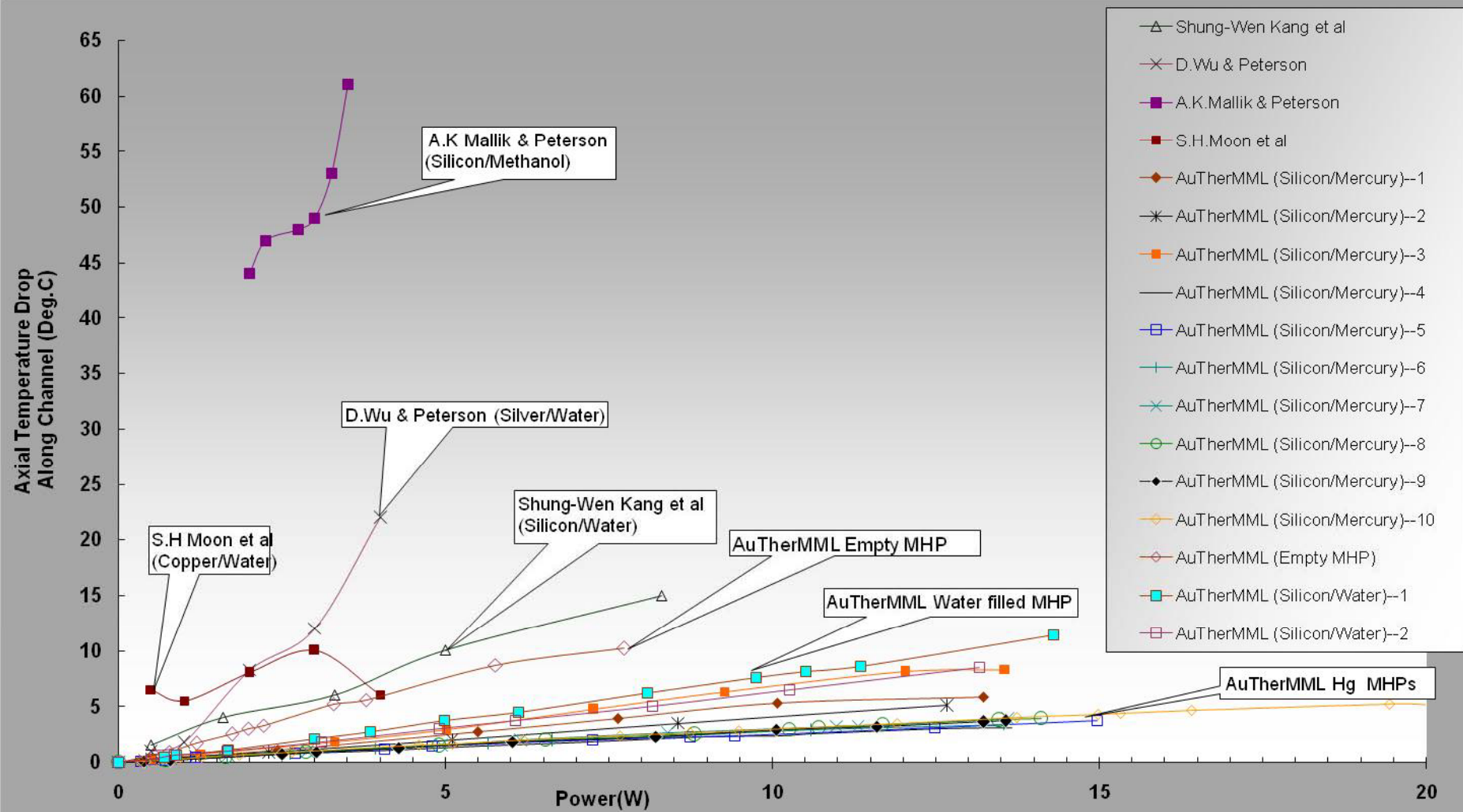
The Liquid Metal Advantage



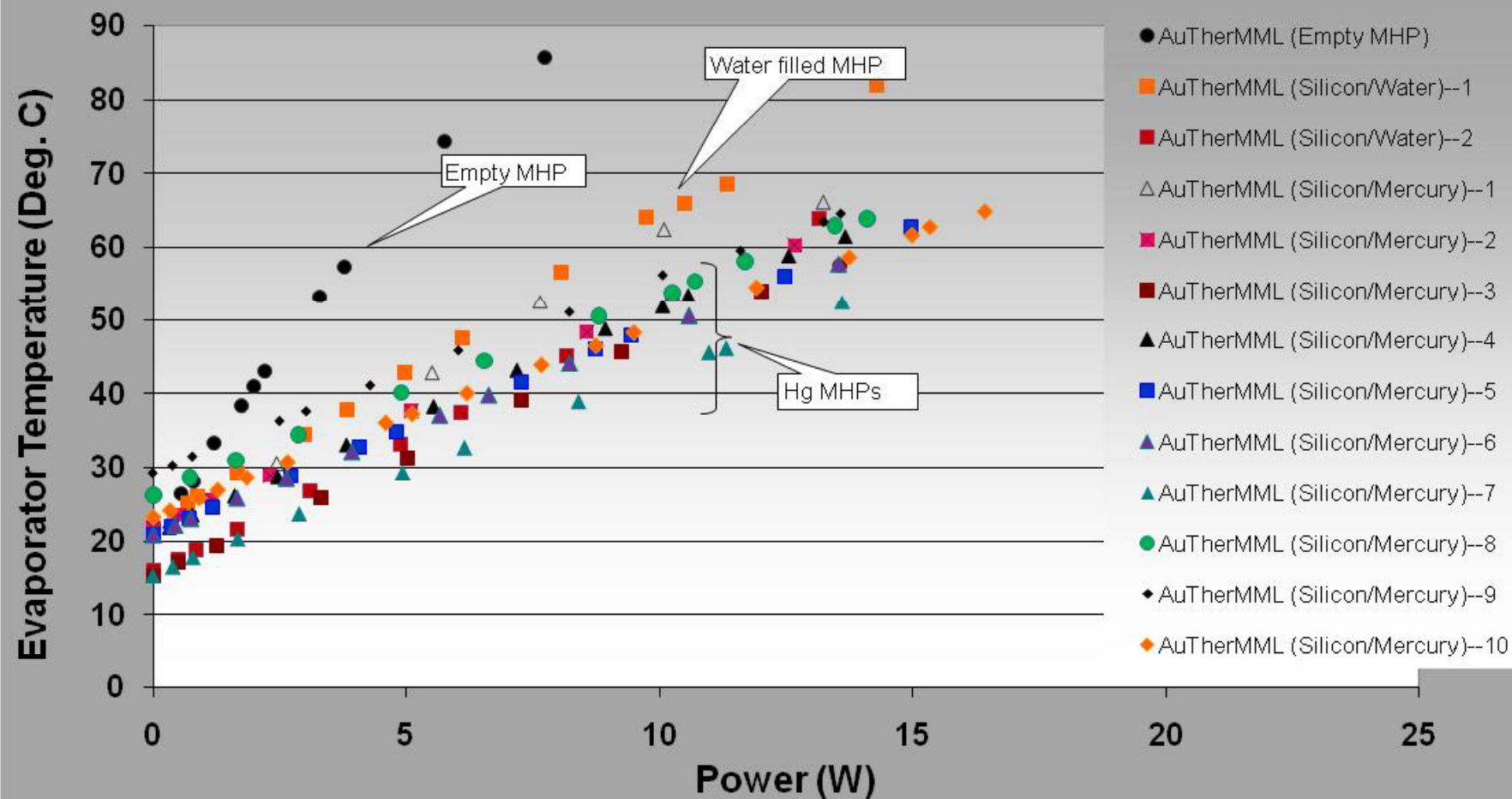
BACKUP SLIDES

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Equivalent Thermal Conductivity

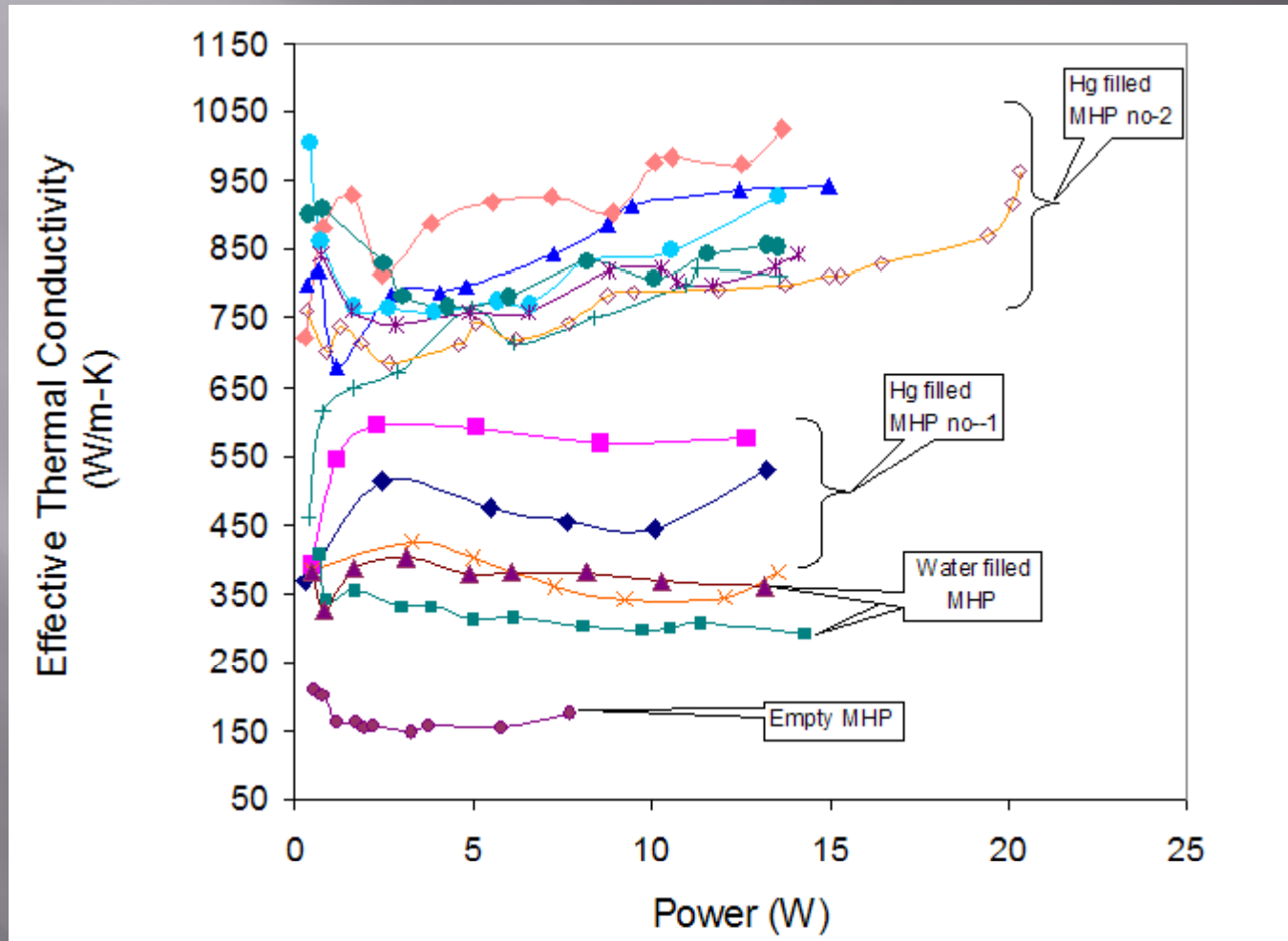


Evaporator Temperature



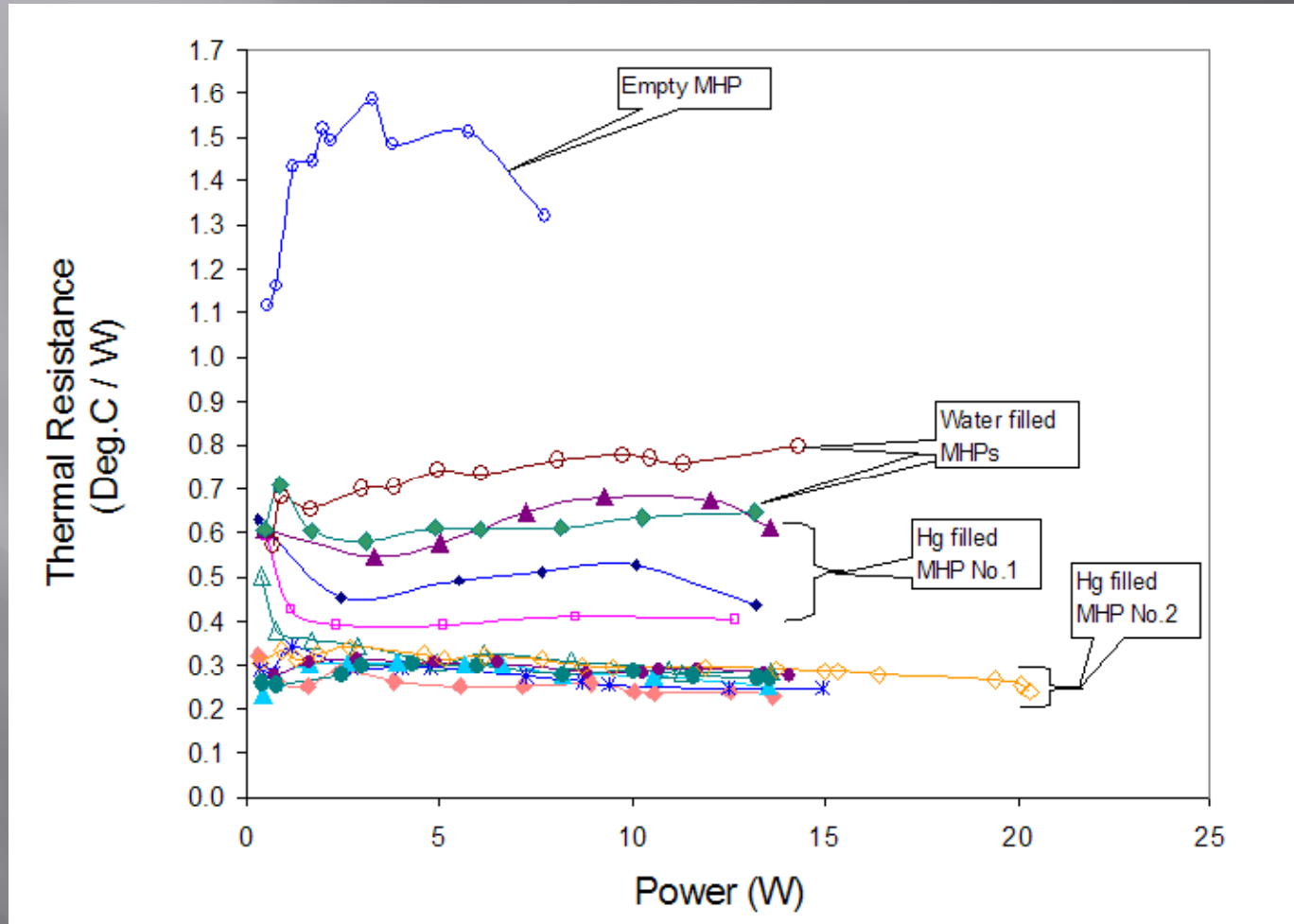
Test Results

- Effective thermal conductivity vs. Power for various MHPs



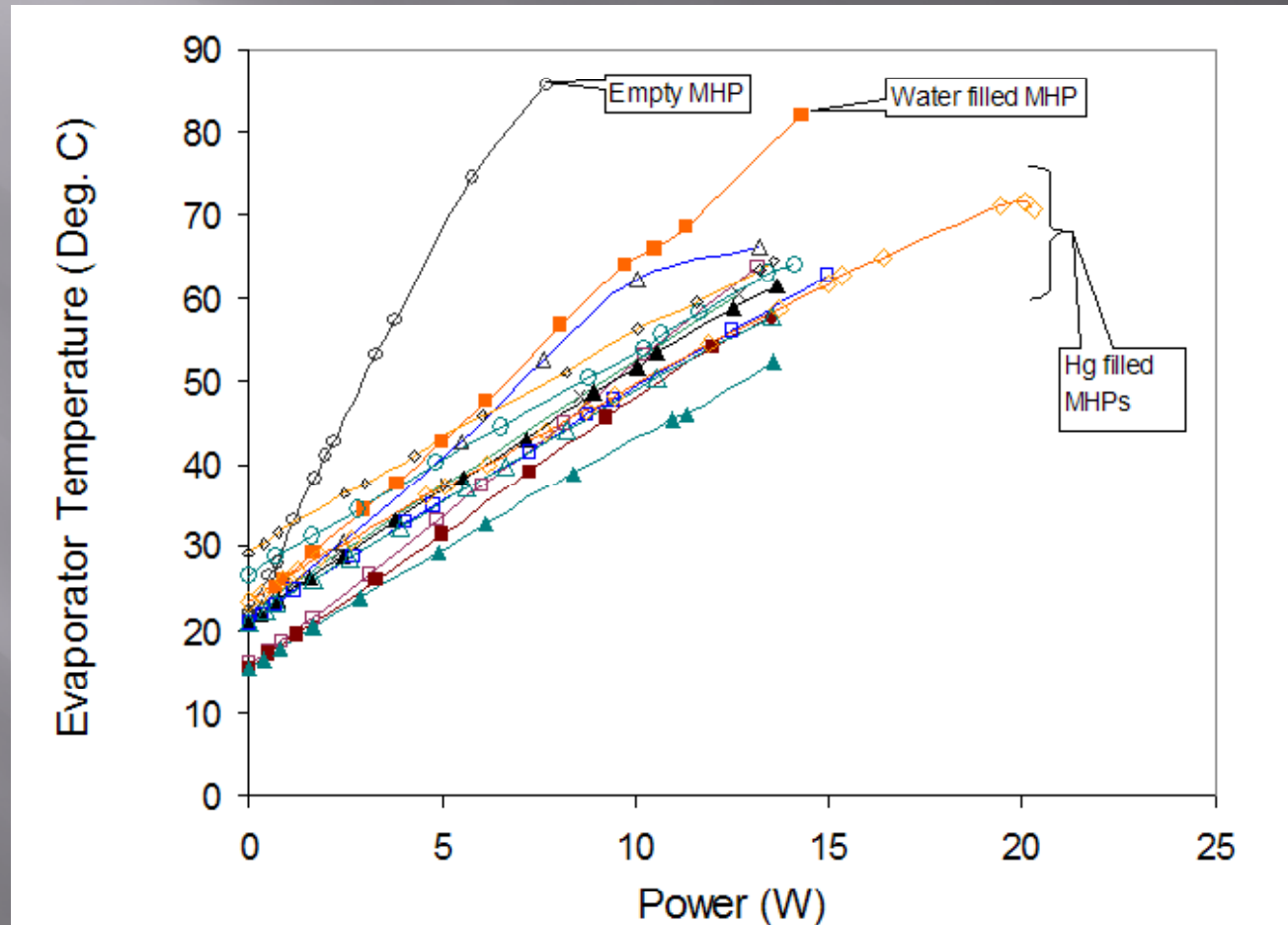
Test Results

Thermal resistance vs. Power



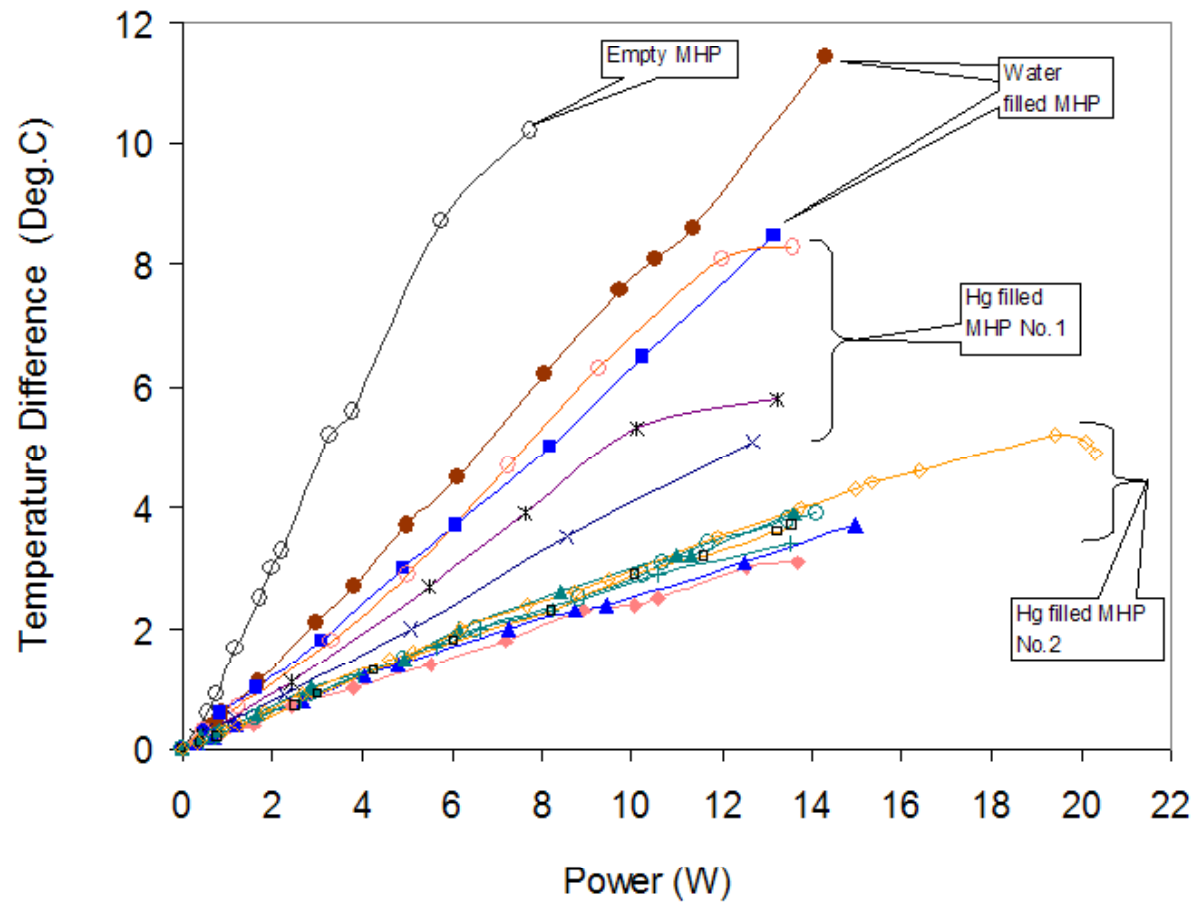
Test Results

- Evaporator temperature vs. Power for various MHPs



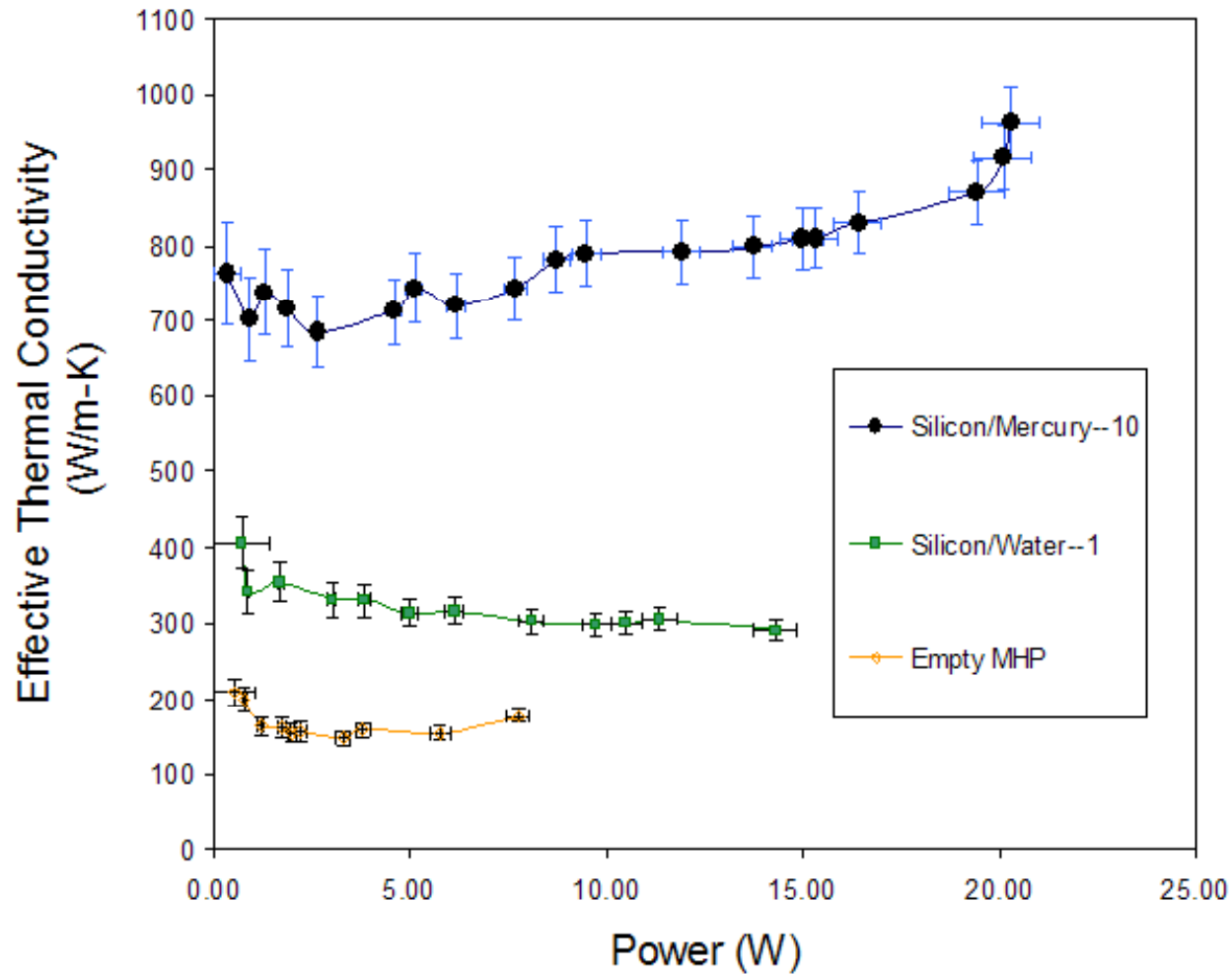
Test Results

□ Temperature difference vs. Power for various MHPs



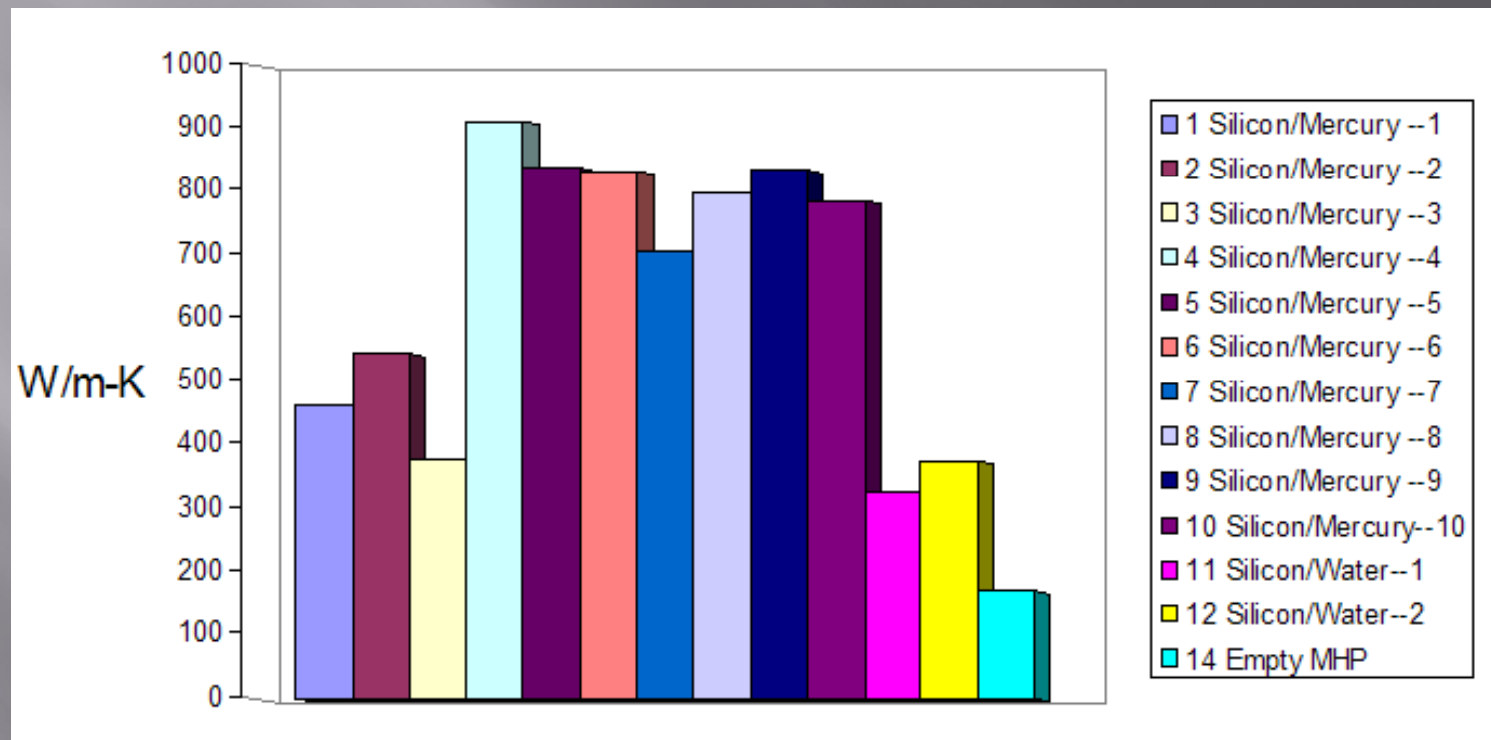
Test Results

□ Uncertainty Analysis



Test Results

- Comparison of average effective thermal conductivities for various MHPs



Test Results

- Enhancement factor : Improvement of the average effective thermal conductivity a charged MHP over that of an empty MHP

